

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of:

Wang, et al.

Serial No.: 10/800,112

Confirmation No.: 8920

Filed:

March 12, 2004

For:

Method of Depositing An

Metal Etch Hardmask

Application

Amorphous Carbon Film for

MAIL STOP AMENDMENT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Group Art Unit: 1765

Examiner:

Mahmoud Dahmene

## CERTIFICATE OF MAILING

37 CFR 1.8

I hereby certify that this correspondence is being deposited on February 6, 2006, with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

02/06/06

Date

Brian K. Hrna

## **RESPONSE TO OFFICE ACTION DATED OCTOBER 5, 2005**

In response to the Office Action dated October 5, 2005, having a shortened statutory period for response extended one-month to expire on February 6, 2006, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/008245/BKH, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. Remarks begin on page 7 of this paper.